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Attorney Docket: 071469-0308969
Client Reference: FKL-020

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT APPLICATION of: FUKIAGE
Application No.: 10/812,354

Confirmation Number: 4104
Group Art Unit: 1762

Filed: March 30, 2004

Examiner:

Title: METHOD OF IMPROVING THE WAFER TO WAFER UNIFORMITY AND
DEFECTIVITY OF A DEPOSITED DIELECTRIC FILM

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Before beginning examination, please amend the above-identified application as follows:

02/17/2005 SZEWDIE1 00000146 033975 10812354
01 FC:1202 50.00 DA